## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

MASUDA, et al

Serial No.:

(not yet assigned)

Filed:

July 11, 2003

For:

PLASMA ETCHING APPARATUS AND PLASMA ETHCING

**METHOD** 

## REAFFIRMATION OF CLAIM FOR PRIORITY

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

July 11, 2003

Sir:

Under the provisions of 35 USC §119 and 37 CFR §1.55, Applicants hereby claim the right of priority based on Japanese Patent Application No. 7-057472, filed in Japan on March 15, 1995.

The certified copy of the above-referred to Japanese Patent Application was filed on May 28, 1996 in prior application 08/611,758, filed March 8, 1996.

Respectfully submitted,

Melvin Kraus

Registration No. 22,466

ANTONELLI, TERRY, STOUT & KRAUS, LLP

MK/cee (703) 312-6600